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Attorney's Docket No. Intel Corporation: 10559-928001/P18717

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Richard Schenker et al.      Art Unit: 2852  
Serial No.: 10/813,453      Examiner: Unknown  
Filed : March 29, 2004      Assignee: Intel Corporation  
Title : LITHOGRAPHY USING CONTROLLED POLARIZATION

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Dear Sir:

Applicants call attention to the attached Information Disclosure Statement and documents listed on form PTO-1449.

This filing is being made before the receipt of a first Office action on the merits. No fee is required.

The documents are in the English language; hence no concise explanation is necessary per Rule 98(a)(3).

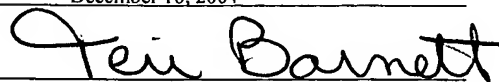
Consideration of the foregoing and enclosures plus the return of a copy of the enclosed form PTO-1449 with the Examiner's initials in the left column per MPEP 609 are earnestly solicited along with an early action on the merits.

CERTIFICATE OF MAILING BY FIRST CLASS MAIL

I hereby certify under 37 CFR §1.8(a) that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage on the date indicated below and is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

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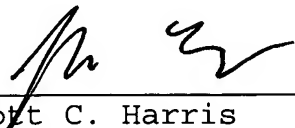
Teri Barnett

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Respectfully submitted,

Date: 12/16/04

  
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Substitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 10559-928001	Application No. 10/813,453
<b>Information Disclosure Statement by Applicant</b> (Use several sheets if necessary) (37 CFR §1.98(b))		Applicant Richard Schenker et al.	
		Filing Date March 29, 2004	Group Art Unit 2852

### U.S. Patent Documents

Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						

### Foreign Patent Documents or Published Foreign Patent Applications

Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
	AI							
	AJ							
	AK							
	AL							
	AM							

### Other Documents (include Author, Title, Date, and Place of Publication)

Examiner Initial	Desig. ID	Document
	AN	Richard Schenker et al., "Material Limitations to 193-nm Lithographic System Lifetimes", SPIE Vol. 2726, pgs. 698-706
	AO	Richard E. Schenker et al., "Ultraviolet-induced densification in fused silica", J. Appl. Phys. 82 (3), August 1, 1997, pgs. 1065-1071
	AP	G. de Zwart et al., "Performance of a Step and Scan System for DUV Lithography", SPIE Vol. 3051, pgs. 817-830
	AQ	

Examiner Signature	Date Considered
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	